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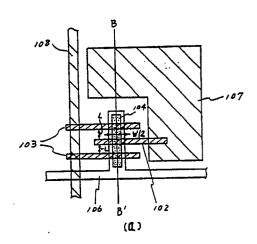
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57) Described is a thin film transistor comprising on

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(54) Thin film transistor.

a substrate (101) a source electrode (103), a drain electrode (102), a semiconductor layer (104) contacting the source and drain electrodes, a gate insulating layer (105) and a gate electrode (106), wherein said source and drain electrodes (103, 102) are formed as parallel elongated strips extending in a first direction, said semiconductor layer (104) and said gate electrode (106) are formed as elongated strips extending in a second direction substantially perpendicular to said frist direction, and said gate electrode (106) completely covering said semiconductor layer (104) through the gate insulating film (105). With this arrangement any shift of the gate electrode (106) mwith respect to source and drain electrodes (103, ◀102), which may occur during manufacturing, does not influence the parasitic capacitances between ingate and source and gate and drain of the transistor. This ensures uniform transistor characteristics where ma plurality of such thin film transistors are employed eas for instance with an active matrix liquid crystal display device.



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FIG. 1



EUROPEAN SEARCH REPORT

EP 89 10 4568

Catacas	Citation of document with indic	ation, where appropriate,	Relevant	CLASSIFICATION OF THE
Category	of relevant passa		to claim	APPLICATION (Int. Cl. 4)
Х	EP-A-0 200 138 (ASAH * Abstract; figures 2	,11-14; column 6,	1,2	H 01 L 29/78 G 02 F 1/133
Υ	line 48 - column 7, line 49 *		1,2	
X	EP-A-0 216 673 (THOMSON-CSF) * Abstract; figure 9 *		1	
Y	FR-A-2 599 559 (GENE * Abstract; figure 4; page 7, line 16 *		1,2	
A	EP-A-0 209 113 (GENE * Abstract; figures 3 page 9, line 23 - pag	A-3C; figure 5;	1,2	
	PATENT ABSTRACTS, vol. 10, no. 289 (E-442)[2345], 2nd October 1986; & JP-A-61 108 171 (TOSHIBA CORP.) 26-05-1986		1	
	* Whole document *		:	TECHNICAL FIELDS SEARCHED (Int. Cl.4)
			·	H 01 L
	The present search report has been	drawn up for all claims		
	Place of search	Date of completion of the sear	1	Examiner
THE	HAGUE	28-02-1990	MTMC	OUN B.J.

- X: particularly relevant if taken alone
 Y: particularly relevant if combined with another document of the same category
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